



## 李伟力

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### 主要研究方向

- (1) 磁性纳米结晶薄膜材料的制备、结构控制、软磁和硬磁特性、隧穿巨磁电阻效应、磁电耦合效应的研究
- (2) 多功能热释电薄膜、介电薄膜材料的研制、电学与光学性质及其应用的研究
- (3) 高介电、巨压电材料的溶胶-凝胶粉体合成及机理研究

### 社会兼职

东北三省 X 射线衍射学会委员；‘科技创新导报’特约编委

### 主要学术成果

文章：

1. **W.L. Li**, J.L. Yang, Y. Zhao, W.D. Fei. Effect of assistant RF plasma on structure and properties of SiCN thin films prepared by RF magnetron sputtering of SiC target. *Journal of Alloys and Compounds* 482(2009) 317–319
2. **Li Weili**, Zheng Xiaohang, Fei Weidong. Fractal growth of Fe-N thin films prepared by magnetron sputtering at elevated temperature. *Vacuum* 83(2009)949-952
3. **W.L. Li**, Q.G. Chi, J.M. Wang, W.D. Fei. Growth behavior of amorphous Ca and La modified PbTiO<sub>3</sub> thin film. *Journal of Non-Crystalline Solids* 354(2008)5014-5017
4. **W.L. Li**, Y. Sun, W.D. Fei. Residual stress and Curie temperature of Fe-N thin films prepared by DC magnetron sputtering at elevated temperature. *Applied Surface Science* 252(2006)4995-5001
5. **W.L. Li**, F. Zheng, W.D. Fei. Effect of assistant RF magnetic field on phase composition of iron nitride film prepared by DC magnetron sputtering process. *Journal of Vacuum Science and Technology A* 24(2006)170-173
6. **W.L. Li**, W.D. Fei, T.Hanabusa. Effect of deposition condition on residual stress of iron nitride thin films prepared by magnetron sputtering and ion implantation. *Applied Surface Science* 252(2006)2847-2852
7. **Li Weili**, Sun Yue, Fei Weidong. Dynamic scaling behavior of iron nitride thin films prepared by magnetron sputtering and ion implantation. *Transactions of Nonferrous Metals Society of China* 15(2005)236-239
8. **W.L. Li**, W.D. Fei, Y. Sun. Effects of implantation conditions on the roughness of N-implanted  $\alpha$ -Fe. *Journal of Materials Science Letters* 21(2002)239-241
9. **W.L. Li**, Y. Sun and W.D. Fei. Effect of implantation voltage on phase composition and surface roughness of  $\alpha$ -Fe surface layer implanted by nitrogen Ion. *Applied Surface Science* 187 (2002) 192-198
10. **W.L. Li**, W.D. Fei, Y. Sun. Grazing Incidence X-ray Scattering and Diffraction Study of the Nitrogen Ion Implantation Layer Produced by Plasma Based Ion Implantation. *Surface and Coatings Technology* 150(2002) 64-69

专利：

李伟力，费维栋，宋文韬，赵瑜，一种壳-芯结构 CaCu<sub>3</sub>Ti<sub>4</sub>O<sub>12</sub> 陶瓷材料及其制备方法。申请号：201010109339. 7